

2812

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Satayadev Patel, et al.

Art Unit: 2812

Serial No.: 10/005,308

Examiner: Not Yet Assigned

Filed: December 3, 2001

For: **METHODS FOR DEPOSITING, RELEASING AND PACKAGING MICRO-ELECTROMECHANICAL DEVICES ON WAFER SUBSTRATES**

INFORMATION DISCLOSURE STATEMENT
PURSUANT TO 37 CFR 1.97(b)

Commissioner for Patents
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Sir:

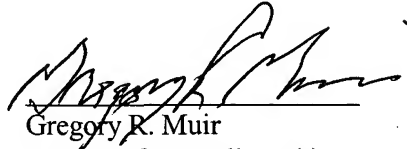
The attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached PTO Form 1449. Copies of the cited references are enclosed.

No fee or certification is required in connection with this Information Disclosure Statement, since it is being submitted prior to the last of (1) issuance of a first official action on the merits and (2) expiration of the three month period following filing of the above-captioned application.

The above information is presented so that the Patent and Trademark Office can determine any materiality thereof to the claimed invention. It is respectfully requested that the information be considered during the prosecution of this application and that the cited documents be listed on the front page of any patent issuing from this application.

The Patent Office is authorized to charge our Deposit Account No. 501516 for any fee which it deems to be required to effect consideration of this statement.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "Gregory R. Muir", is written over a horizontal line.

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| INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 1 OF 6 | | | ATTY. DOCKET NO. P19-US | | SERIAL NO. 10/005,308 | | |
| | | | APPLICANT Satayadev R. Patel, et al. | | | | |
| | | | FILING DATE 12/03/01 | | GROUP 2812 | | |
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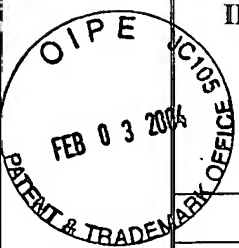
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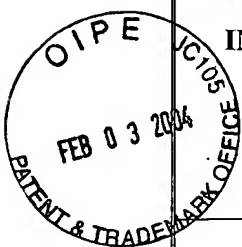
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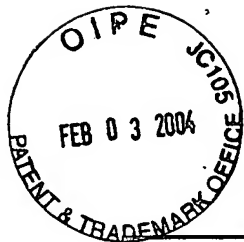
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